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APPLICANTS

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** CONTINUING DATA *****

This application is a CON of 09/739,905 12/20/2000 PAT 6,607,986

** FOREIGN APPLICATIONS *****

JAPAN 11-372006 12/28/1999

IF REQUIRED, FOREIGN FILING LICENSE GRANTED

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| Foreign Priority claimed | <input checked="" type="checkbox"/> yes <input type="checkbox"/> no | STATE OR COUNTRY | SHEETS | TOTAL | INDEPENDENT |
|---------------------------------|---|---------------------|-----------|-----------|-------------|
| 35 USC 119 (a-d) conditions met | <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after <i>J. Aitken</i> <i>M.H.</i> Allowance Examiner's Signature Initials | JAPAN | DRAWING 8 | CLAIMS 20 | CLAIMS 3 |
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ADDRESS

22852
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TITLE

Dry etching method and semiconductor device manufacturing method

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